



# Simulation of a Floating Gate Device in standard CMOS process for Dosimetry applications

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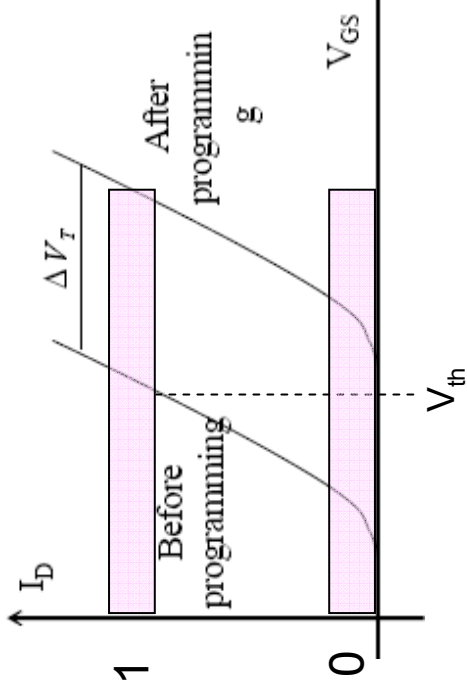
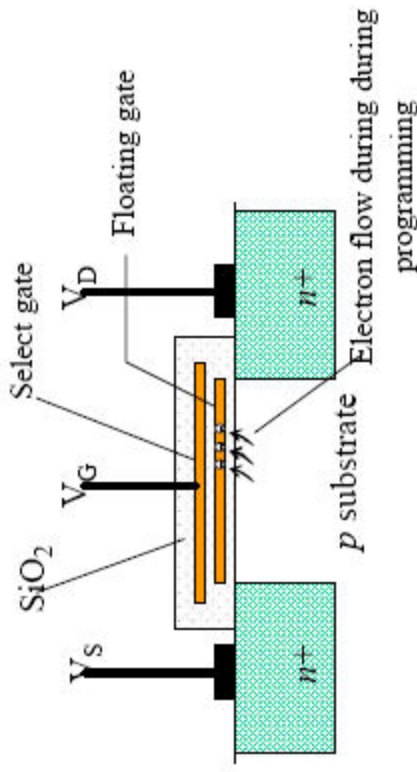
# Outlook

- Introduction to Floating gate devices
- Use as radiation sensors for dosimetry applications
- Simulation results
- Conclusions



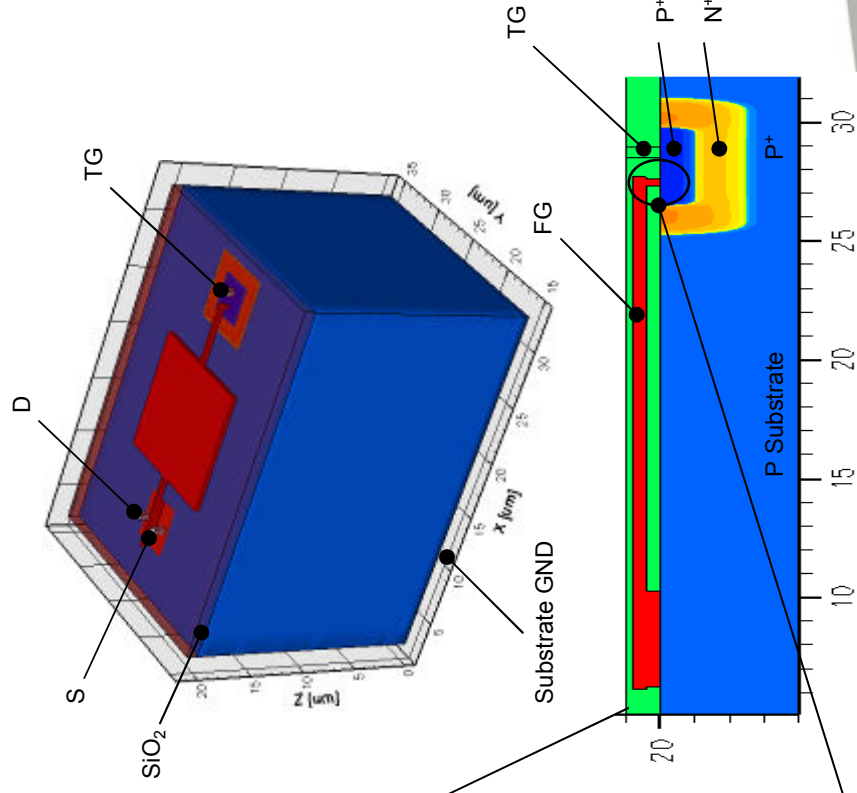
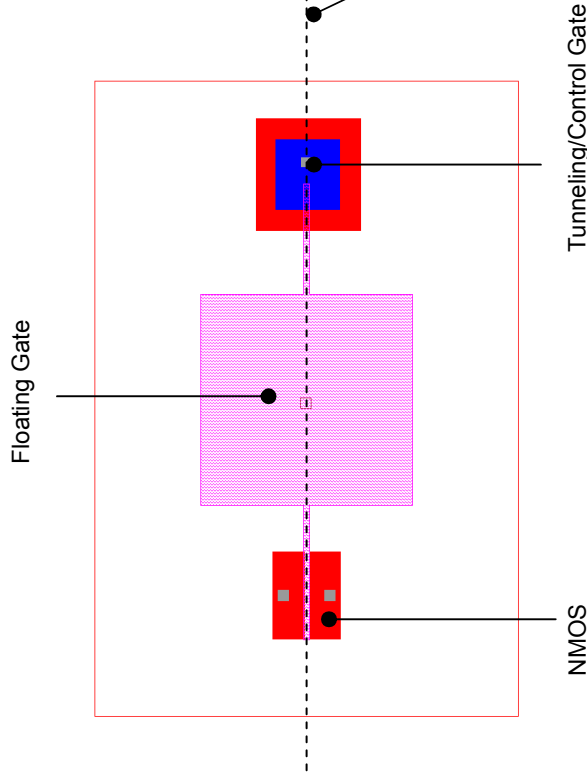
# Introduction to Floating Gate Devices

Dual poly floating gate devices have been in use for many years as NVM elements (EPROM, FLASH)

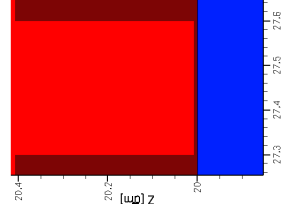


They have been proposed as radiation sensors for dosimetry or as basic blocks for analogue applications

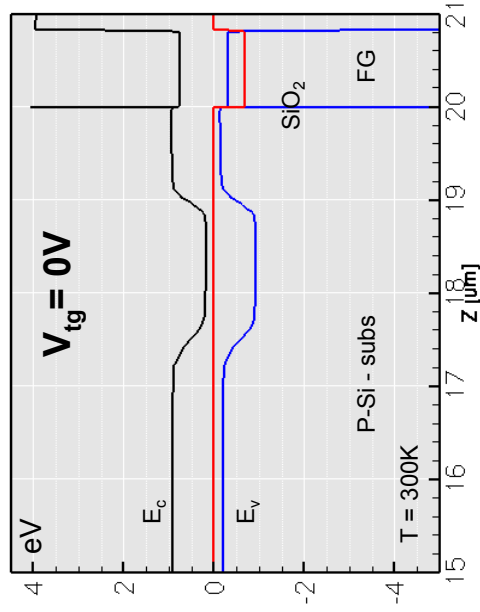
# Floating Gate Device



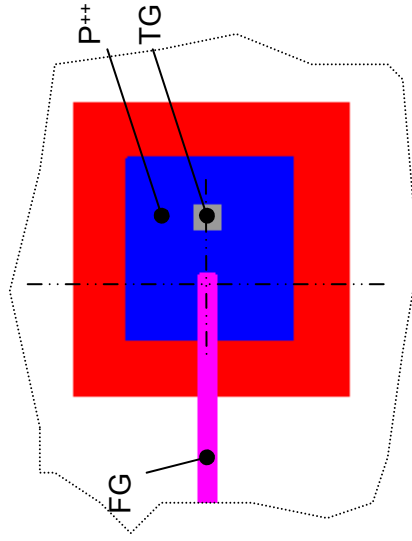
Radiation sensor from a standard single poly CMOS process used for NVM memory



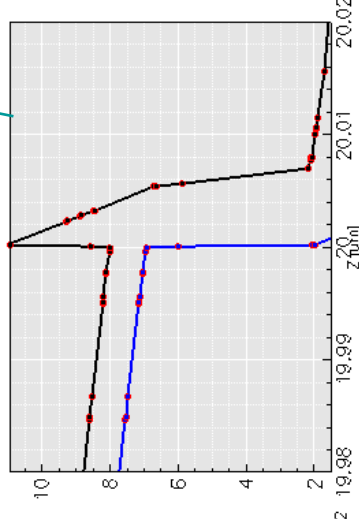
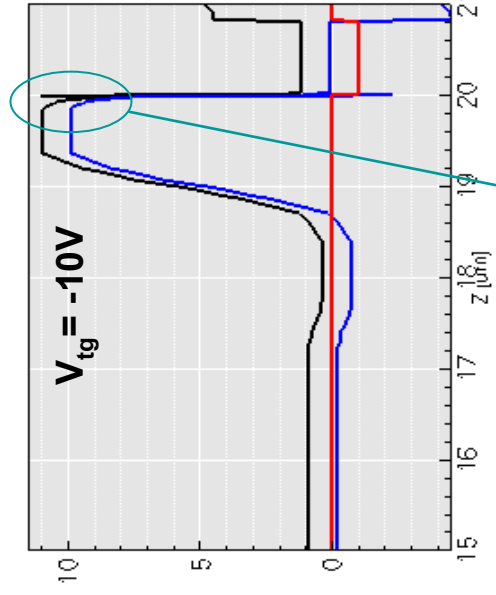
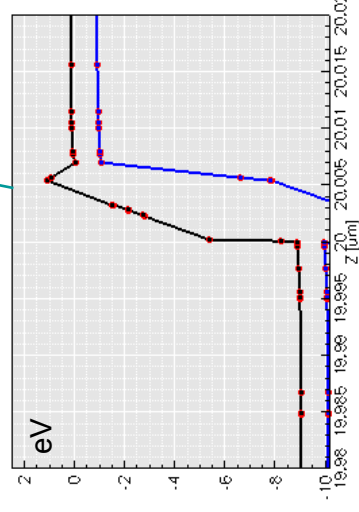
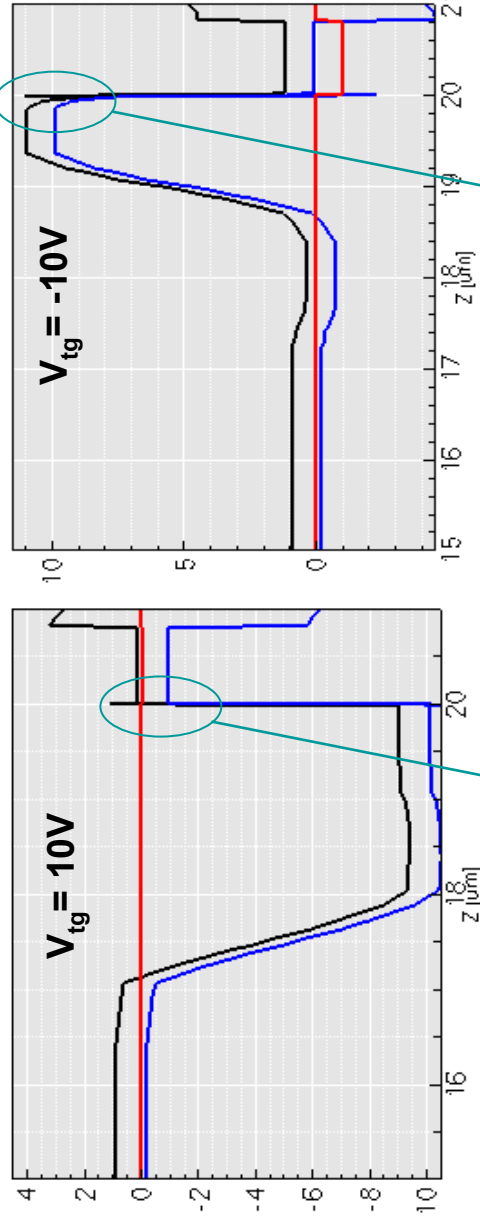
# Device Programming



Tunneling through  $\text{SiO}_2$  is enabled by applying a voltage bias to TG



X section through tunneling area  
(subs = 0V, D = S = 0V)

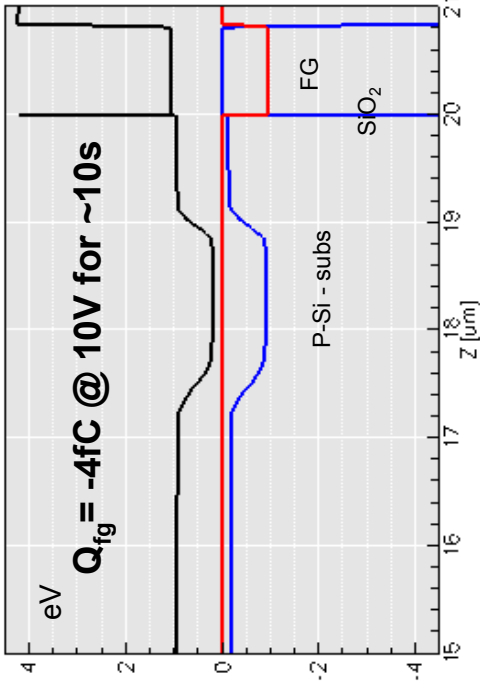
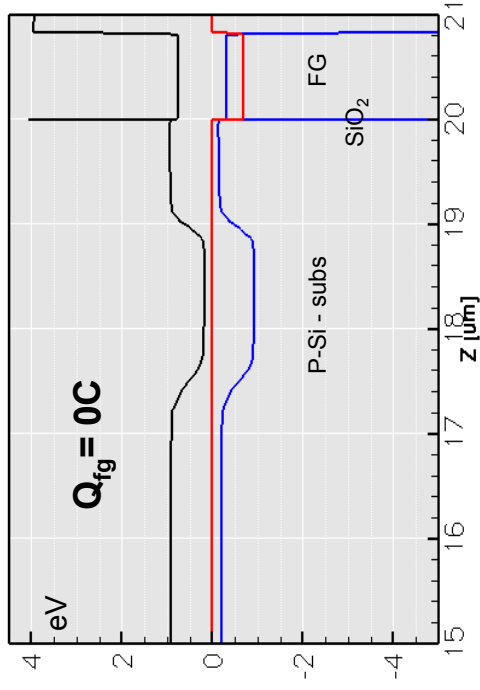


Band diagrams

Debye length  $\sim 5\text{nm}$

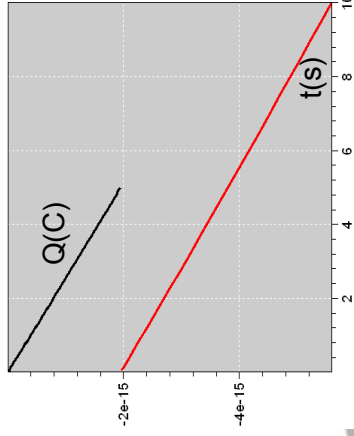
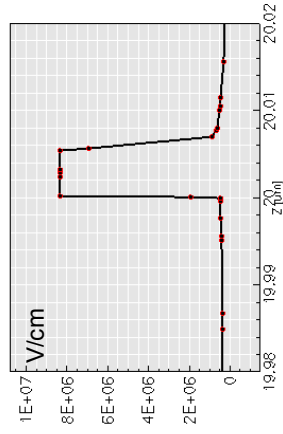


# Device Programming



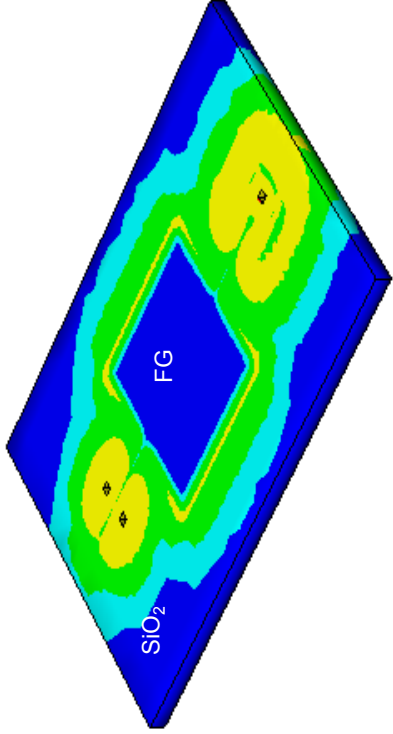
$$j_n = \frac{qm_c k}{2\pi^2 \hbar^3} \int_0^\infty Y(E) \left\{ T(0) \ln \left[ \exp \left[ \frac{E_{Fn}(0) - E_c(0) - E}{kT(0)} \right] + 1 \right] \right. \\ \left. - T(d) \ln \left[ \exp \left[ \frac{E_{Fn}(d) - E_c(0) - E}{kT(d)} \right] + 1 \right] \right\} dE$$

Direct tunneling  $\approx$  FN for  $F_{ox} > 6 \text{Mv/cm}$

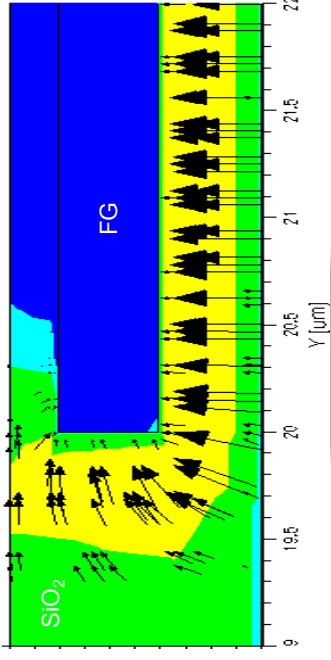
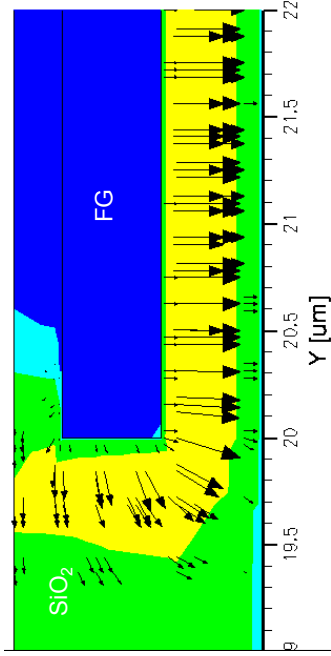
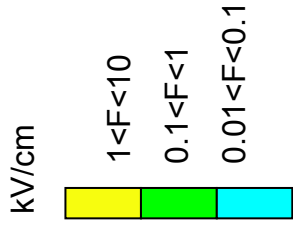
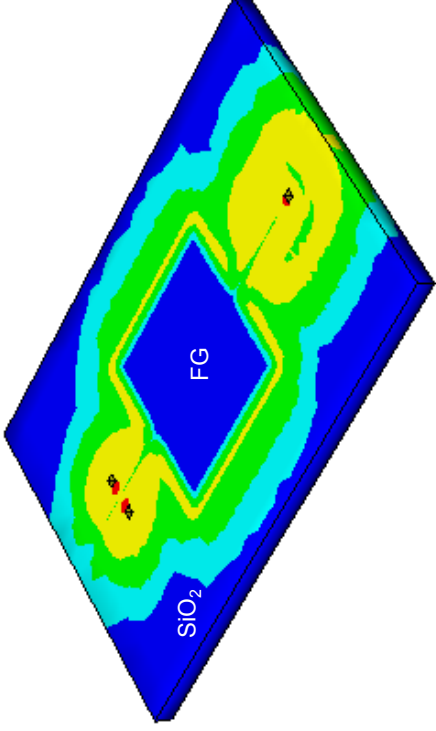


# Electrical characteristics

$Q_{fg} = 0C$   
 $\Phi_{FG} = -0.228V$



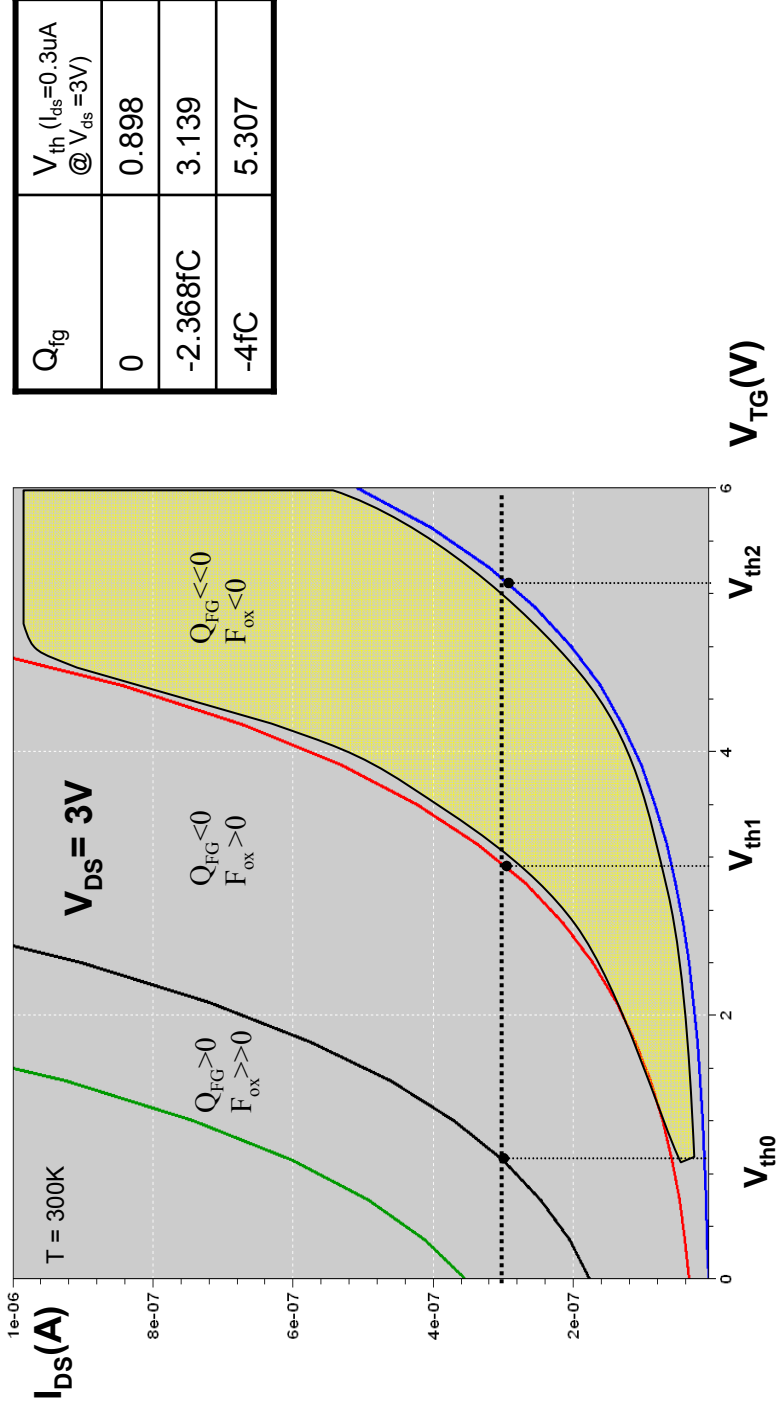
$Q_{fg} = -4fC$   
 $\Phi_{FG} = -0.506V$



The intensity and direction of the SiO<sub>2</sub> electric field can be changed with Q stored in FG



# Electrical characteristics

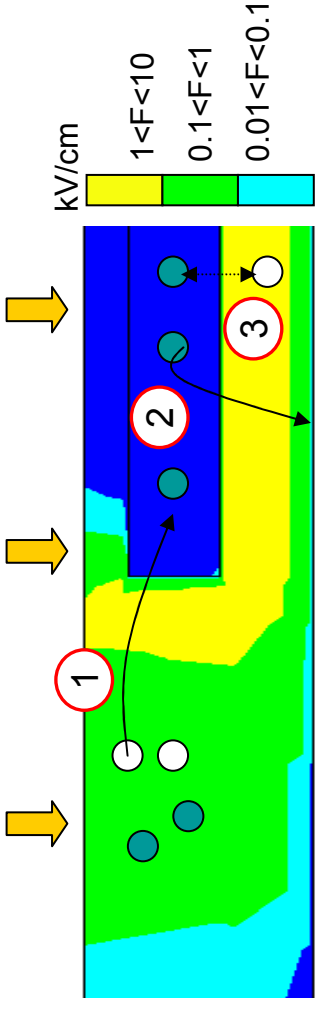
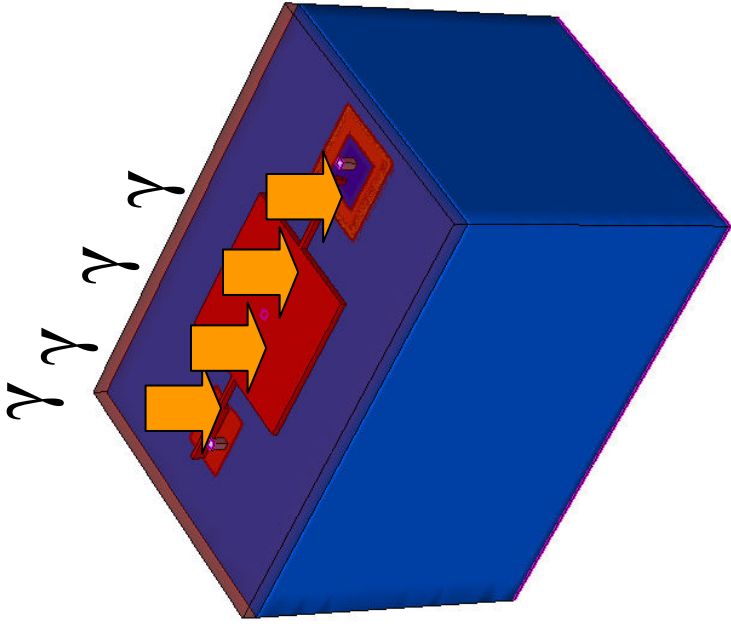


The charge stored in the FG allows to change the threshold voltage in both directions



# Radiation Detection

The deposited radiation in  $\text{SiO}_2$  alters the internal electric field ( $F_{\text{ox}}$ ): this affects the electrical characteristics of the device ( $V_{\text{th}}$ )

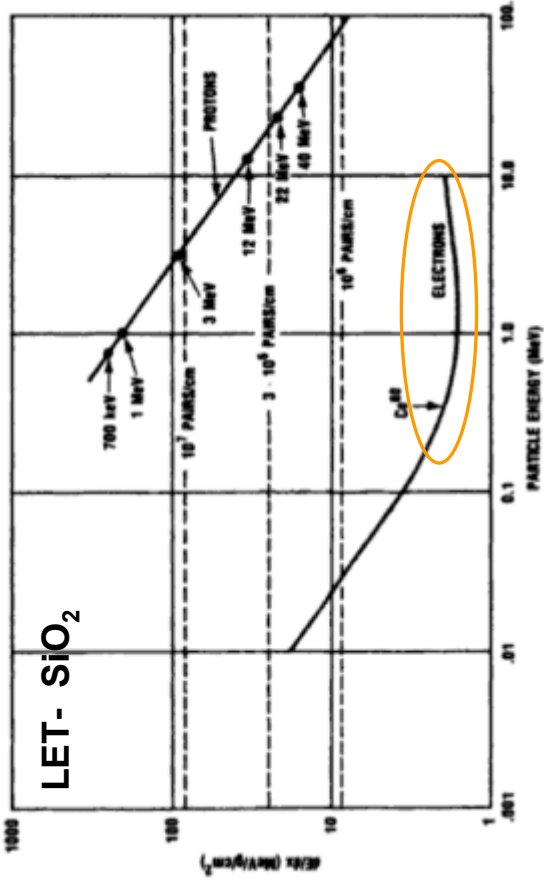
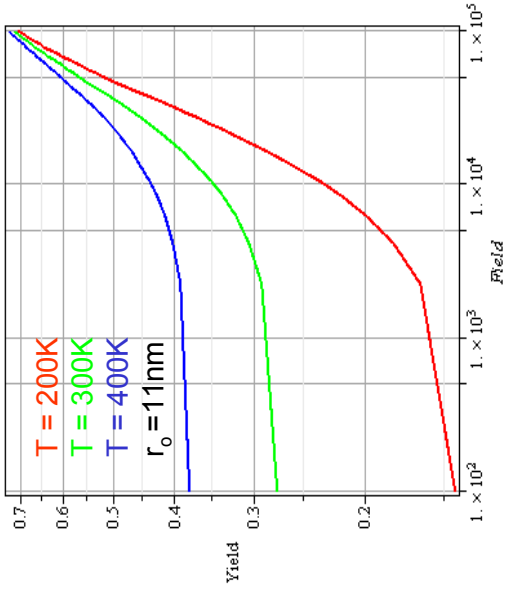


Three main mechanisms of radiation sensing:

1. FG discharge via charge injection
2. FG discharge direct
3. Holes trapping (requires knowledge on  $\text{SiO}_2$  processing)

FG discharge by holes collection from  $\text{SiO}_2$ , generated by gamma radiation

# Radiation Detection



low LET particles: Onsager model

probability of an electron escaping recombination

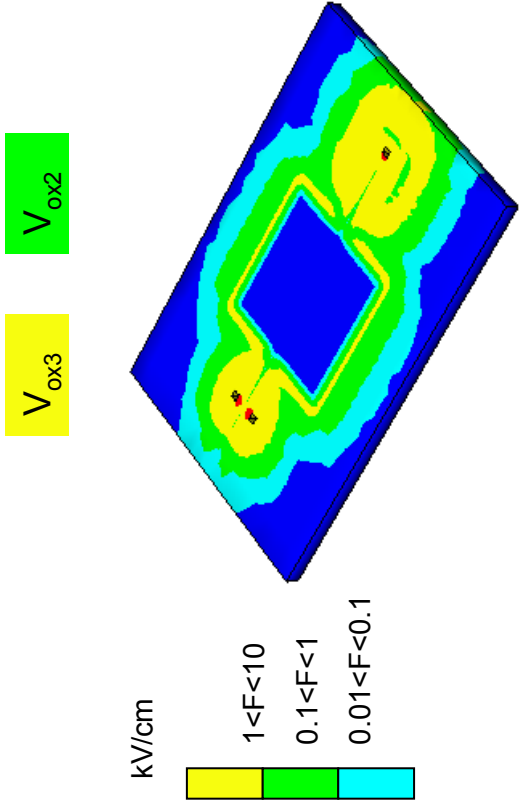
$$Y(F_{ox}, T, r_0) = K^{-1} e^{(-A)} e^{(-K)} \sum_{m=0}^{\infty} \frac{A^m}{m!} \sum_{n=0}^{\infty} \sum_{l=m+n+1}^{\infty} \frac{K^l}{l!}$$

$$K = \frac{qF_{ox}r_0}{kT}$$

$$A = \frac{r_c}{r_0}, r_c = \frac{q^2}{4\pi\epsilon_{SiO_2} kT}$$



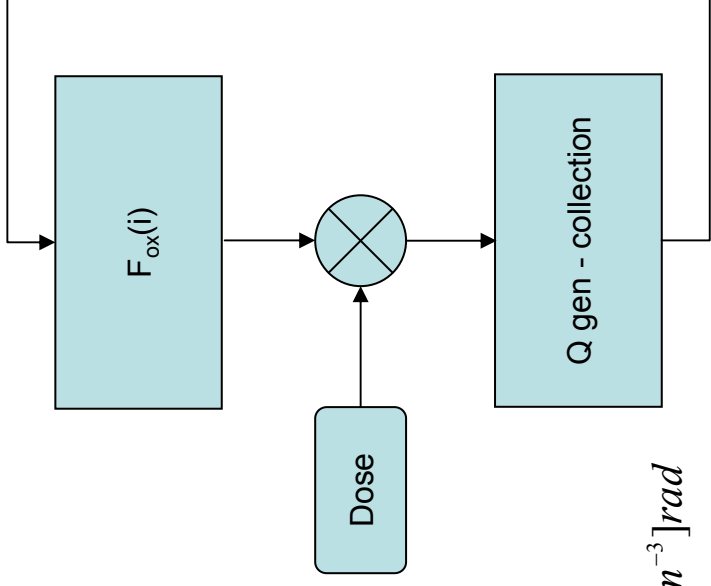
# Radiation Detection



$$Q_{coll} = Q_{rad} \cdot \sum_i V_{oxi}(i) \cdot Y_{ox}(i) \quad , i > 1$$

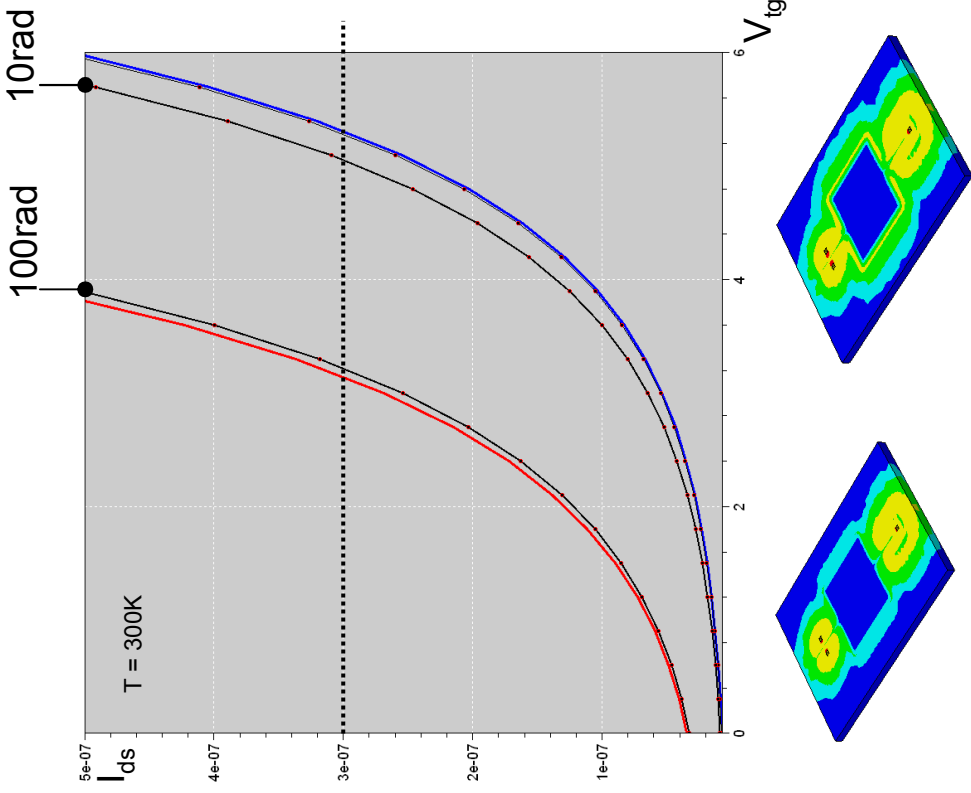
$$Q_{rad} = \frac{D \cdot \rho_{SiO_2} \cdot 6.24 \cdot 10^7 [MeV \cdot g^{-1}] \cdot 2.2 [g \cdot cm^{-3}]}{W_{SiO_2} [eV]} \cong 8 [\mu m^{-3}] rad$$

The collection of holes by FG generated in SiO<sub>2</sub> is a function of F<sub>ox</sub>



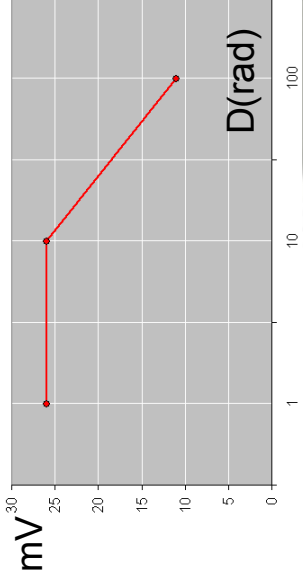
The F<sub>ox</sub> is updated after new charge collection to estimate effect of decreasing FG charge

# Radiation Detection



D	$V_{th}$ @ $I_{ds}=0.3\mu A$
0	5.307
1rad	5.281
10rad	5.056
100rad	3.214

D	Sensitivity ( $\Delta V_{th}/rad$ )@ $V_{ds}=3V$
0	26mV
10rad	26mV
100rad	11mV



The sensitivity decreases as the FG discharges

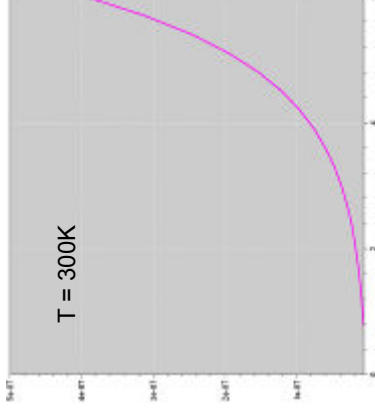
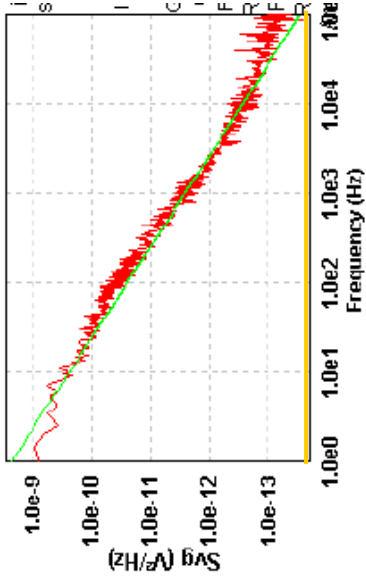


# Noise analysis

The gate referred noise of the device has estimated spectral density:

$$V^2_{noise} = 4kT \frac{2}{3} \frac{1}{g_m} + \frac{K_f}{WL} \frac{1}{f^\alpha} \approx 4.8e-14 + \frac{2.5e-9}{f^{0.8}}$$

$$\int_{1e-3}^{10} V_{noise} df \approx 330 \mu V_{rms}$$



Typ. Flicker noise spectrum

$$W/L = 10/0.18$$

$$g_m(V_{th}) \approx 2.3e-7 A/V$$

D	Sensitivity ( $\sqrt{V_{th}/rad}$ )@ $V_{ds}=3V, T = 300K$	Max resolution (Rad)
0	26mV	0.0384
10rad	26mV	0.0384
100rad	11mV	0.091

Assuming a minimum readout time of 10 readings/sec over a period of 1hr and 3 times the RMS value as minimum detectable  $V_{th}$  change gives the resolution in rad of the device





## Conclusions

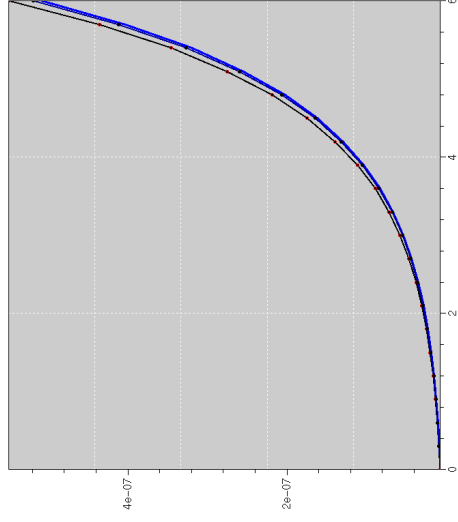
The device simulations results suggest the use of this technology for radiation dosimetry  
The sensitivity is estimated to be  $\ll 1\text{rad}$  for 1 to 10MeV photons  
The dynamic range will also depend on the device layout  
The technology is CMOS standard and allows the integration on the same substrate of the readout electronics

### Planned activities:

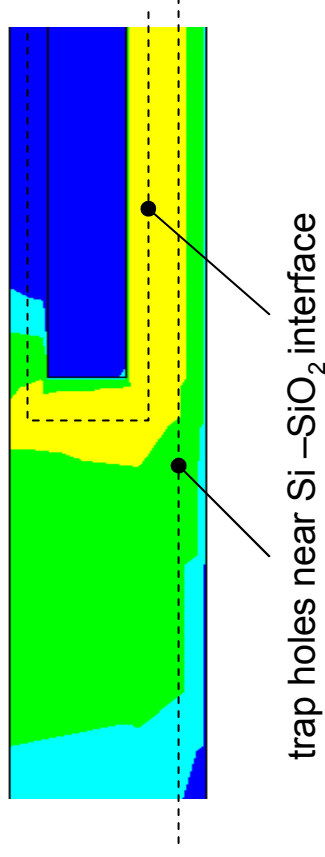
Further studies of charge collection mechanisms and transport in the  $\text{SiO}_2$   
Negotiation with foundry to obtain test devices  
Grant application for funding for an in vivo dosimetry project

# Backup slides

The hole transport in SiO<sub>2</sub>: hopping and trap assisted transport produce dispersive transport



Simulation with  $Q_{ox} = 1e12cm^{-3}$   $\mathcal{N}_{th} = 101mV$   
Assuming holes trapped uniformly in SiO<sub>2</sub>

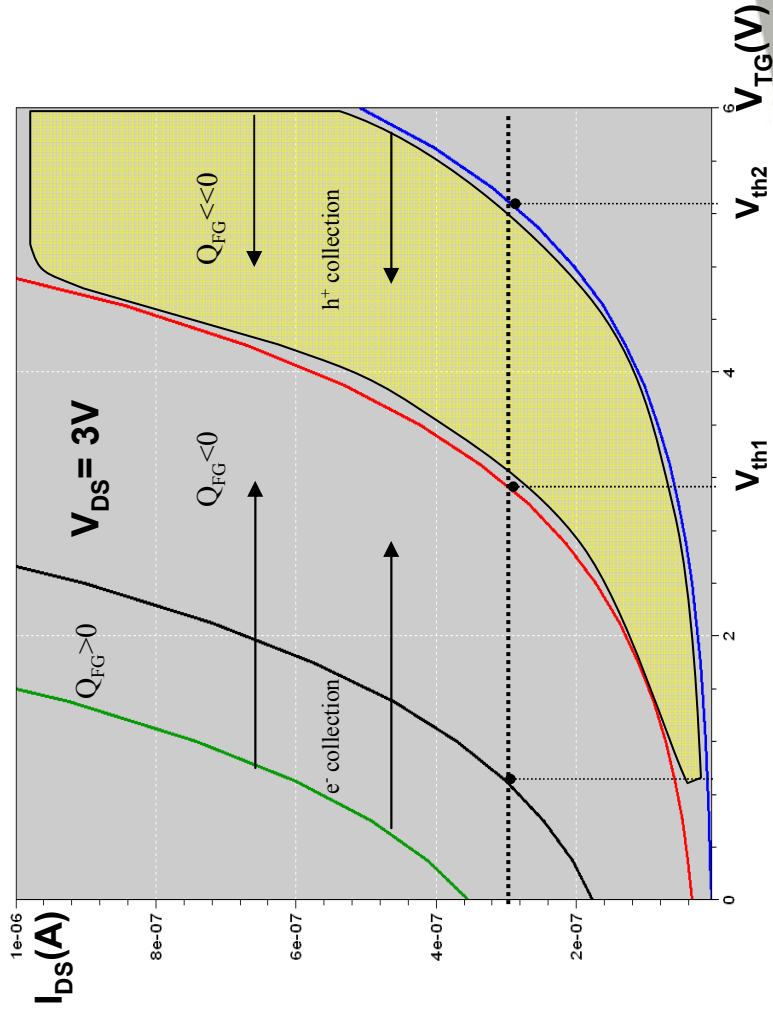


At low doses, the hole trapping will take place mostly near the interfaces SiO<sub>2</sub>/Si: need more information on SiO<sub>2</sub> processing to estimate hole trap density and levels



# Backup slides

In principle electron could be collected instead of holes: this would *increase* the threshold voltage





## Backup slides

Depletion (enhancement) effects at the boundaries are taken into account  
Quantization effects due to band bending to be studied (but unlikely to be so relevant for this application)

